

3723

|  |  |  |  |                                   |  |
|--|--|--|--|-----------------------------------|--|
| <b>AMENDMENT TRANSMITTAL LETTER (Large Entity)</b> |  |  |  | Docket No.<br>35013.4000          |  |
| Applicant(s): Tim Dyer, et al.                     |  | Filing Date<br>APR 12 2002<br><i>APR 12 2002</i> |  | Examiner<br>McDonald, Shantese L. |  |
| Serial No.<br>09/836,426                           |  | Group Art Unit<br>3723                           |  |                                   |  |

Invention: **CHEMICAL MECHANICAL POLISHING METHOD AND APPARATUS FOR REMOVING MATERIAL FROM A SURFACE OF A WORKPIECE THAT INCLUDES LOW-K MATERIAL**

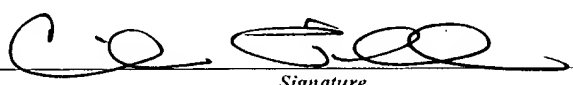
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TO THE ASSISTANT COMMISSIONER FOR PATENTS, TECHNOLOGY CENTER R3700

Transmitted herewith is an amendment in the above-identified application.  
The fee has been calculated and is transmitted as shown below.

| CLAIMS AS AMENDED  |                                     |                             |                                |         |                   |
|--|-------------------------------------|-----------------------------|--------------------------------|---------|-------------------|
|  | CLAIMS REMAINING<br>AFTER AMENDMENT | HIGHEST #<br>PREV. PAID FOR | NUMBER EXTRA<br>CLAIMS PRESENT | RATE    | ADDITIONAL<br>FEE |
| TOTAL CLAIMS   | 33 -                                | 33 =                        | 0 x                            | \$18.00 | \$0.00            |
| INDEP. CLAIMS  | 6 -                                 | 6 =                         | 0 x                            | \$84.00 | \$0.00            |
| Multiple Dependent Claims (check if applicable) <input type="checkbox"/> |                                     |                             |                                |         | \$0.00            |
| <b>TOTAL ADDITIONAL FEE FOR THIS AMENDMENT</b>                           |                                     |                             |                                |         | <b>\$0.00</b>     |

☒ No additional fee is required for amendment.  
☐ Please charge Deposit Account No. \_\_\_\_\_ in the amount of \_\_\_\_\_  
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☒ Any additional filing fees required under 37 C.F.R. 1.16.  
☒ Any patent application processing fees under 37 CFR 1.17.



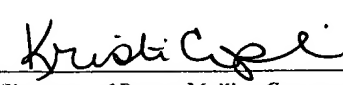
Signature

**Cynthia L. Pillote - Reg. No. 42,999**  
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Dated: 4/04/02

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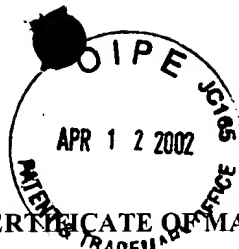


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**Kristi Coplin**

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Kristi Cole

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APR 16 2002

IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE

TECHNOLOGY CENTER R3700

Applicant(s): Tim Dyer, et al.

Attorney Docket No.: 35013.4000

Serial No.: 09/836,426

Group Art Unit: 3723

Filed: April 17, 2001

Examiner: McDonald, Shantese L.

TITLE: CHEMICAL MECHANICAL POLISHING METHOD AND APPARATUS  
FOR REMOVING MATERIAL FROM A SURFACE OF A WORKPIECE  
THAT INCLUDES LOW-K MATERIAL

RESPONSE

Commissioner for Patents  
Box Non-Fee Amendment  
Washington, D.C.

Dear Sir:

Applicants hereby timely respond to the Office Action mailed January 16, 2002, within the three-month shortened statutory period to respond. Please consider the following remarks.

REMARKS

In the January 16, 2002 Office Action, the Examiner acknowledged that claims 7-8, 11, 14-16, 21-23, and 29-31 include allowable subject matter and rejected claims 1-6, 9-10, 12-13, 17-20, 24-28, and 32-33. Applicants submit that all pending claims are allowable over the cited references and therefore request that the Examiner reconsider the claim rejections, in view of the arguments set forth herein, and allow all pending claims 1-33.